

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.10813543
Filing DateMarch 3, 2004
Confirmation No.8087
Inventor..... Gealy, F. Daniel
AssigneeMicron Technology, Inc.
Group Art Unit 1792
Examiner Chen, Keath T.
Attorney's Docket No. MI22-3685
Title:..... Method for Reducing Physisorption During Atomic Layer Deposition

INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO/SB/08

The attached Form PTO/SB/08 is submitted in compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, and your attention is directed to the references listed on the attached Form PTO/SB/08. No admission is made regarding whether the submitted references are prior art.

A fee in the amount of \$180.00 will be paid to cover the fee specified under 37 C.F.R. § 1.17(p).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 6/30/08

By: 

Robert C. Hyta
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